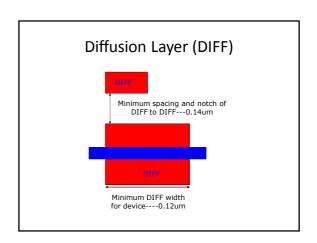
Layout Rules UMC 90um 1P9M Process OT-02/09, v2011



Nwell Layer (NWEL) • A: minimum Nwell width ----0.52um • B: spacing and notch of Nwell to Nwell of equal potential ----0 or >=0.52um • C: minimum NwEL enclosure of P+ DIFF ---0.21um • D: minimum NWEL to P+ DIFF --0.16um • E: minimum NWEL enclosure of N+ DIFF ---0.16um • F: minimum NWEL to N+ DIFF ---0.21um NOTE: NWEL patterns must be orthogonal

